

566.41191X00



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Y. KURATA, et al.

Application No.: 10/049,672

Filed: February 15, 2002

For: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL
POLISHING, AND METHOD OF POLISHING

Examiner: 1765

Group: D. Deo

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

July 8, 2004

Sir:

In response to the Office Action mailed January 8, 2004, please amend the above-identified application as listed in the following, and as set forth on the following pages:

Amendments to the Claims; and

Remarks are included following the amendments.